

PATENT ASSIGNMENT

Electronic Version v1.1
 Stylesheet Version v1.1

SUBMISSION TYPE:	NEW ASSIGNMENT
NATURE OF CONVEYANCE:	ASSIGNMENT
CONVEYING PARTY DATA	
Name	Execution Date
Celerity, Inc.	06/15/2009
RECEIVING PARTY DATA	
Name:	Brooks Instrument, LLC
Street Address:	407 West Vine Street
City:	Hatfield
State/Country:	PENNSYLVANIA
Postal Code:	19440
PROPERTY NUMBERS Total: 1	
Property Type	Number
Patent Number:	7490518
CORRESPONDENCE DATA	
Fax Number:	(214)758-1550
Phone:	214.758.3502
Email:	dcollins@pattonboggs.com
<i>Correspondence will be sent to the e-mail address first; if that is unsuccessful, it will be sent via US Mail.</i>	
Correspondent Name:	Darren W. Collins
Address Line 1:	2000 McKinney Avenue
Address Line 2:	Suite 1700
Address Line 4:	Dallas, TEXAS 75201
ATTORNEY DOCKET NUMBER:	030578.0157
NAME OF SUBMITTER:	Darren W. Collins
Total Attachments: 37 source=Brooks-Celerity Patent Assignment#page1.tif source=Brooks-Celerity Patent Assignment#page2.tif source=Brooks-Celerity Patent Assignment#page3.tif	

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PATENT ASSIGNMENT

For and in consideration of the sum of Ten Thousand Dollars (\$10,000.00) and other good and valuable consideration, the receipt of which is hereby acknowledged, Celerity, Inc., with offices at 2645 Zanker Road, Suite 101, San Jose, CA 95134 (hereinafter "Assignor"), hereby assigns, sells, transfers and sets over effective as of June __, 2009 to Brooks Instrument, LLC, with offices at 407 West Vine Street, Hatfield, PA 19440-0903 (hereinafter "Assignee"), its successors and assigns the entire rights, title and interests in and to the patents and patent applications set forth in Exhibit A, attached hereto and made a part hereof; in and to the inventions covered by such patents and applications; in and to any divisional, continuation, continuation-in-part, or reissue applications corresponding to such patents and applications and any reexamination of such patents and applications; and the right to claim priority based on the filing dates of such applications under the International Convention for the Protection of Industrial Property, the Patent Cooperation Treaty, the European Patent Convention, and all other treaties of like purpose; together with all claims for profits or damages due or accrued by reason of past, present, or future infringements of such patents and applications, with the right to sue for, and collect the same for, Assignee's own use and benefit, and for the benefit of Assignee's successors, assigns, and legal representatives. Assignor will perform such lawful acts and execute all further documents as Assignee may reasonably request, at Assignee's expense, to effectuate fully the assignment of such patents and applications.

IN WITNESS WHEREOF, Assignor has caused this Assignment to be signed by a duly authorized officer.

Celerity, Inc (Assignor)

By: THarris

Printed name: Tim Harris

Title: Chief Executive Officer

Date: 6-15-09

EXHIBIT A

SCHEDULE OF PATENTS AND TRADEMARKS

Patents

Product Category	Title	Case Number	Sub Case	Case Type	Country	Application No.	Filing Date	Patent No.	Issue Date
Pending	METHOD AND SYSTEM FOR FLOW MEASUREMENT AND VALIDATION OF A MASS FLOW CONTROLLER	C2044-7024	KR	PCT	KR	2007-7003058	07-Jul-05		
Granted	METHOD AND SYSTEM FOR FLOW MEASUREMENT AND VALIDATION OF A MASS FLOW CONTROLLER	C2044-7024	19	PRI	US	10/887,591	09-Jul-04	7412986	19-Aug-08
Abandoned	METHOD AND SYSTEM FOR FLOW MEASUREMENT AND VALIDATION OF A MASS FLOW CONTROLLER	C2044-7024	TW	ORD	TW	94123260	08-Jul-05	I278606	11-Apr-07
Pending	METHOD AND SYSTEM FOR FLOW MEASUREMENT AND VALIDATION OF A MASS FLOW CONTROLLER	C2044-7024	JP	PCT	JP	520494/2007	07-Jul-05		
Abandoned	METHOD AND SYSTEM FOR FLOW MEASUREMENT AND VALIDATION OF A MASS FLOW CONTROLLER	C2044-7024	EP	PCT	EP	5772286	07-Jul-05		
Abandoned	METHOD AND SYSTEM FOR FLOW MEASUREMENT AND VALIDATION OF A MASS FLOW CONTROLLER	C2044-7024	CN	PCT	CN	580029957.8	07-Jul-05		

Product Category	Case Title	Case Number	Sub Case	Case Type	Court	Application No.	Filing Date	Issue Date
Inactive	METHOD AND SYSTEM FOR FLOW MEASUREMENT AND VALIDATION OF A MASS FLOW CONTROLLER	C2044-7024	WO	ORD	PCT	US2005/024084	07-Jul-05	
Abandoned	METHOD AND SYSTEM FOR FLOW MEASUREMENT AND VALIDATION OF A MASS FLOW CONTROLLER	C2044-7024	SG	PCT	SG	200700059-9	07-Jul-05	
Granted	Method and System for Flow Measurement and Validation of Mass Flow Controller	C2044-7024	30	CIP	US	10/946,031	21-Sep-04	16-Sep-08
Abandoned	RATE OF RISE SENSOR	C1138-7007		PRI	US			
Granted	SYSTEM AND METHOD FOR MEASURING FLOW	C2044-7017	19	PRI	US	11/012750	15-Dec-04	19-Dec-06
Granted	SYSTEM AND METHOD FOR MEASURING FLOW	C2044-7017	20	CON	US	11/341826	27-Jan-06	30-Oct-07
Abandoned	SYSTEM AND METHOD FOR MEASURING FLOW	C2044-7017	TW	ORD	TW	94144182	14-Dec-05	
Abandoned	SYSTEM AND METHOD FOR MEASURING FLOW	C2044-7017	SG	PCT	SG	200702892-1	29-Nov-05	
Pending	SYSTEM AND METHOD FOR MEASURING FLOW	C2044-7017	KR	PCT	KR	2007-7016097	29-Nov-05	
Abandoned	SYSTEM AND METHOD FOR MEASURING FLOW	C2044-7017	JP	PCT	JP	546711/2007	29-Nov-05	
Abandoned	SYSTEM AND METHOD FOR MEASURING FLOW	C2044-7017	EP	PCT	EP	5826076.1	29-Nov-05	
Abandoned	SYSTEM AND METHOD FOR MEASURING FLOW	C2044-7017	CN	PCT	CN	580043027.8	29-Nov-05	
Inactive	SYSTEM AND METHOD FOR MEASURING FLOW	C2044-7017	WO	ORD	PCT	US2005/043148	29-Nov-05	
Abandoned	METHOD AND SYSTEM FOR WAFER TEMPERATURE CONTROL	C2044-7026	EP	PCT	EP	5811910.8	13-Oct-05	

Patent No.	Case No.	Sub Case No.	Applicant No.	Priority Date	Patent No.			
Published	HBSC	C2044-7026	US	PCT	US	11/664,550	03-Apr-07	
Abandoned	HBSC	C2044-7026	TW	ORD	TW	94135754	13-Oct-05	
Abandoned	HBSC	C2044-7026	SG	PCT	SG	200701620-7	13-Oct-05	
Inactive	HBSC	C2044-7026	WO	ORD	PCT	US2005/037130	13-Oct-05	
Abandoned	HBSC	C2044-7026	MY	ORD	MY	PI20070586	16-Apr-07	
Abandoned	HBSC	C2044-7026	JP	PCT	JP	536969/07	13-Oct-05	
Abandoned	HBSC	C2044-7026	CN	PCT	CN	580034213.5	13-Oct-05	
Abandoned	HBSC	C2044-7026	KR	PCT	KR	2007-7008380	13-Oct-05	
Inactive	Heater	C2044-7001	EP	PCT	EP	99945336.8	03-Sep-99	1118051

17-Mar-04

Patent No.	Priority	Class	Sub	Pub	Pub	Pub	Pub	Pub	Pub	Pub
Pending	Heater	C2044-7001	JP	PCT	JP	2000-569296	03-Sep-03			
Abandoned	Heater	C2044-7001	NL	EPP	NL	99945336.8	03-Sep-99	1118051		17-Mar-04
Abandoned	Heater	C2044-7001	TW	ORD	TW	88115459	08-Sep-99	131484		01-May-01
Abandoned	Heater	C2044-7001	GB	EPP	GB	99945336.8	03-Sep-99	1118051		17-Mar-04
Granted	Heater	C2044-7001	19	PRI	US	09/150458	09-Sep-98	6078030		20-Jun-00
Expired	LFC	C1138-7012	0	PRO	US	60/707628	12-Aug-05			
Abandoned	LFC	C1138-7012	TW	ORD	TW	95129519	11-Aug-06			
Abandoned	LFC	C1138-7012	SG	PCT	SG	200703341-8	11-Aug-06			
Inactive	LFC	C1138-7012	WO	ORD	PCT	US2006/031579	11-Aug-06			

Case No.	Case Title	Case Number	Sub Case	Cur. Type	Applicant	Pub. No.	Pub. Date
Abandoned	LFC	C1138-7012	MY	ORD	MY	PI20063906	11-Aug-06
Pending	LFC	C1138-7012	KR	PCT	KR	2007-7011301	11-Aug-06
Pending	LFC	C1138-7012	JP	PCT	JP	526275/2008	31-May-07
Abandoned	LFC	C1138-7012	CN	PCT	CN	680001605.6	11-Aug-06
Abandoned	LFC	C1138-7012	10	ORD	US	11/503873	11-Aug-06
Abandoned	LFC	C1138-7012	EP	PCT	EP	6801387.9	11-Aug-06
Abandoned	LFC	C1138-7002	US	PRI	US	07/906922	30-Jun-92
Unfiled	LFC	C1138-7010	19	PRI	US		
Inactive	LFC	C1138-7009	WO	ORD	PCT	US2006/031291	10-Aug-06
Abandoned	LFC	C1138-7009	TW	ORD	TW	95129338	10-Aug-06
Expired	LFC	C1138-7009	0	PRO	US	60/707574	12-Aug-05
Granted	LFC	C1138-7009	10	ORD	US	11/502308	10-Aug-06
Abandoned	LFC	C1138-7009	20	CON	US	12/148537	18-Apr-08
Abandoned	LFC	C1138-7009	MY	ORD	MY	PI20063862	10-Aug-06
Abandoned	LFC	C1138-7006	EP	PCT	EP	5762540.2	28-Jun-05

Patent No.	Sub Class	Capacity	Priority	Pub No.	Pub Date	App No.	App Date	Pub No.	Pub Date
Inactive	LFC	C1138-7006	20	CON	US				
Granted	LFC	C1138-7006	19	PRI	US	10/878974	28-Jun-04	7117104	03-Oct-06
Abandoned	LFC	C1138-7006	TW	ORD	TW	94121591	28-Jun-05		
Granted	LFC	C1138-7006	SG	PCT	SG	541292	28-Jun-05	128389	29-Feb-08
Inactive	LFC	C1138-7006	WO	ORD	PCT	US2005/022944	28-Jun-05		
Abandoned	LFC	C1138-7006	MY	ORD	MY	PI20052927	28-Jun-05		
Pending	LFC	C1138-7006	JP	PCT	JP	519361/2007	28-Jun-05		
Abandoned	LFC	C1138-7006	CN	PCT	CN	0580027755.X	28-Jun-05		
Pending	LFC	C1138-7006	KR	PCT	KR	2007-7001933	28-Jun-05		
Abandoned	MFC	C2044-7007	NL	EPP	NL	951066	20-Jun-00	1214635	02-Apr-03
Abandoned	MFC	C2044-7007	FR	EPP	FR	951066	20-Jun-00	1214635	02-Apr-03
Granted	MFC	C2044-7007	20	CON	US	10/062080	31-Jan-02	6714878	30-Mar-04
Granted	MFC	C2044-7007	19	PRI	US	09/351120	10-Jul-99	6389364	14-May-02
Abandoned	MFC	C2044-7007	GB	EPP	GB	951066	20-Jun-00	1214635	02-Apr-03

Status	Inventor	Case Number	Sub Class	Case Title	Applicant No.	Date	Priority
				CONTROLLER			
Abandoned	MFC	C2044-7007	TW	ORD	TW	89113530	10-Jul-00 NI-131920 03-Sep-01
Abandoned	MFC	C2044-7007	SG	PCT	SG	200108041-5	20-Jun-00 85973 27-Feb-04
Pending	MFC	C2044-7007	JP	PCT	JP	2001-510060	20-Jun-00
Abandoned	MFC	C2044-7007	CN	PCT	CN	810184.1	20-Jun-00 810184.1 19-Oct-05
Abandoned	MFC	C2044-7007	DE	EPP	DE	951066	20-Jun-00 60001977.2 02-Apr-03
Granted	MFC	C2044-7007	KR	PCT	KR	2002-7000234	20-Jun-00 10-0684539 13-Feb-07
Inactive	MFC	C2044-7007	EP	PCT	EP	951066	20-Jun-00 1214635 02-Apr-03
Abandoned	MFC	C2044-7007	IT	EPP	IT	951066	20-Jun-00 1214635 02-Apr-03
Expired	MFC	C2044-7046	NL	ORD	NL	8400089	11-Jan-84 193641 04-May-00
Abandoned	MFC	U0128-7008	GB	EPC	GB	94930532	30-Sep-94 722552 04-Jul-01

Patent No.	Title	IPC Class.	Pub. No.	Pub. Date	App. No.	App. Date	IPC Class.	Pub. No.	Pub. Date
	FLUID								
Granted	APPARATUS FOR HANDLING PROCESS FLUID	U0128-7008	5803507	08-Sep-98	08/557378	13-Nov-95	CON	US	
Abandoned	APPARATUS FOR HANDLING PROCESS FLUID	U0128-7008	722552	04-Jul-01	94930532	30-Sep-94	EPC	NL	
Abandoned	APPARATUS FOR HANDLING PROCESS FLUID	U0128-7008			701790/1996	30-Sep-94	PCT	KR	
Abandoned	APPARATUS FOR HANDLING PROCESS FLUID	U0128-7008	3431631	23-May-03	07-510916	30-Sep-94	PCT	JP	
Abandoned	APPARATUS FOR HANDLING PROCESS FLUID	U0128-7008	722552	04-Jul-01	94930532	30-Sep-94	EPC	IT	
Abandoned	APPARATUS FOR HANDLING PROCESS FLUID	U0128-7008	69427645.6	04-Jul-01	94930532	30-Sep-94	EPC	DE	
Abandoned	APPARATUS FOR HANDLING PROCESS FLUID	U0128-7008	722552	04-Jul-01	94930532	30-Sep-94	EPC	FR	
Inactive	APPARATUS FOR HANDLING PROCESS FLUID	U0128-7008	722552	04-Jul-01	94930532	30-Sep-94	PCT	EP	
Pending	ATTITUDE INSENSITIVE FLOW DEVICE SYSTEM AND METHOD	C2044-7023			2007-7002945	07-Jul-05	PCT	KR	
Granted	ATTITUDE INSENSITIVE FLOW DEVICE SYSTEM AND METHOD	C2044-7023	7412336	12-Aug-08	11/788,201	19-Apr-07	CON	US	
Granted	ATTITUDE INSENSITIVE FLOW DEVICE SYSTEM AND METHOD	C2044-7023	7222029	22-May-07	10/887048	08-Jul-04	PRJ	US	
Abandoned	ATTITUDE INSENSITIVE FLOW DEVICE SYSTEM AND METHOD	C2044-7023			94123274	08-Jul-05	ORD	TW	

Inactive	MFC	ATTITUDE INSENSITIVE FLOW DEVICE SYSTEM AND METHOD	C2044- 7023	WO	ORD	PCT	US2005/024085	07-Jul-05	
Abandoned	MFC	ATTITUDE INSENSITIVE FLOW DEVICE SYSTEM AND METHOD	C2044- 7023	JP	PCT	JP	520495/2007	07-Jul-05	
Abandoned	MFC	ATTITUDE INSENSITIVE FLOW DEVICE SYSTEM AND METHOD	C2044- 7023	EP	PCT	EP	5772203.5	07-Jul-05	
Abandoned	MFC	ATTITUDE INSENSITIVE FLOW DEVICE SYSTEM AND METHOD	C2044- 7023	CN	PCT	CN	2.0058002293e+011	07-Jul-05	
Pending	MFC	ATTITUDE INSENSITIVE FLOW DEVICE SYSTEM AND METHOD	C2044- 7023	SG	PCT	SG	564483	07-Jul-05	
Expired	MFC	ELECTROMAGNETIC VALVE WITH PERMANENT MAGNET ARMATURE	C1138- 7013	19	PRI	US	711280	22-Oct-85	01-Sep-87
Abandoned	MFC	FLOW CONTROLLER, PARTS OF FLOW CONTROLLER, AND RELATED METHOD	C2044- 7032	SG	PCT	SG	584541	20-Nov-95	27-Apr-99
Abandoned	MFC	FLOW CONTROLLER, PARTS OF FLOW CONTROLLER, AND RELATED METHOD	C2044- 7032	42	DIV	US	08/686231	23-Jul-96	
Granted	MFC	FLOW CONTROLLER, PARTS OF FLOW CONTROLLER, AND RELATED METHOD	C2044- 7032	41	DIV	US	08/685260	23-Jul-96	22-Dec-98
Inactive	MFC	FLOW CONTROLLER, PARTS OF FLOW CONTROLLER, AND RELATED METHOD	C2044- 7032	EP	PCT	EP	95940785.9	20-Nov-95	07-Jun-00
Granted	MFC	FLOW CONTROLLER, PARTS OF FLOW CONTROLLER, AND RELATED METHOD	C2044- 7032	40	DIV	US	08/685322	23-Jul-96	16-Jun-98

Patent Status	Class	Subclass	Pub. No.	Pub. Date	App. No.	App. Date	Pub. No.	Pub. Date	App. No.	App. Date
Granted	MFC		C2044-7032	US	PCT (CIP)	US	2365159	20-Nov-95	5901741	11-May-99
Abandoned	MFC		C2044-7032	19	PRI	US	08/365861	29-Dec-94	5660207	26-Aug-97
Abandoned	MFC		C2044-7032	GB	EPP	GB	95940785.9	20-Nov-95	800672	07-Jun-00
Abandoned	MFC		C2044-7032	TW	ORD	TW	84112299	20-Nov-95	NI-081535	05-Nov-03
Inactive	MFC		C2044-7032	WO	ORD	PCT	US1995/015157	20-Nov-95		
Abandoned	MFC		C2044-7032	KR	PCT	KR	1997-7004536	20-Nov-95	323958	28-Jan-02
Abandoned	MFC		C2044-7032	JP	PCT	JP	1995-520980	20-Nov-95	3717520	09-Sep-05
Abandoned	MFC		C2044-7032	IT	EPP	IT	95940785.9	20-Nov-95	800672	07-Jun-00
Abandoned	MFC		C2044-7032	FR	EPP	FR	95940785.9	20-Nov-95	800672	07-Jun-00
Abandoned	MFC		C2044-7032	CN	PCT	CN	95197568.4	20-Nov-95	ZL95197568	30-Jun-04

Patent No.	Class	Sub Class	Case No.	App. No.	Pub. No.	Pub. Date	Grant Date			
Abandoned	MFC		C2044-7032	1C	DIV	CN	410038447.4	20-Nov-95	410038447.4	29-Aug-07
Abandoned	MFC		C2044-7032	DE	EPP	DE	95940785.9	20-Nov-95	69517447	07-Jun-00
Abandoned	MFC		C2044-7045	2G	EDV	GB	99108928.5	20-Nov-95		
Abandoned	MFC		C2044-7045	2D	EDV	DE	99108928.5	20-Nov-95		
Abandoned	MFC		C2044-7045	F2	EDV	FR	99108928.5	20-Nov-95		
Abandoned	MFC		C2044-7045	E2	DIV	EP	99108928.5	20-Nov-95	940741	09-Jan-08
Inactive	MFC		U0128-7035	WO	ORD	PCT	US2003/022643	18-Jul-03		
Abandoned	MFC		U0128-7035	20	CON	US	10/988,173	12-Nov-04		
Expired	MFC		U0128-7035		PRO	US	60/397461	19-Jul-02		
Abandoned	MFC		U0128-7035	KR	PCT	KR	2005-7000895	18-Jul-03		
Pending	MFC		U0128-7035	JP	PCT	JP	523170/2004	18-Jul-03		
Published	MFC		U0128-7035	EP	PCT	EP	3765796.2	18-Jul-03		
Abandoned	MFC		U0128-7035	CN	PCT	CN	3817189.9	18-Jul-03	3817189.9	12-Dec-07
Granted	MFC		U0128-7035	10	ORD	US	10/623147	18-Jul-03	6826953	07-Dec-04

Patent No.	Sub Class	Class	Code	Country	App No.	Priority	Pub No.	Pub Date	Grant Date
	7035								
Pending	MFC	U0128-7040	KR	PCT	KR	2005-7018084	25-Mar-04		09-May-06
Published	MFC	U0128-7040	20	CON	US	11/856,585	17-Sep-07		11-Oct-05
Granted	MFC	U0128-7040		PRI	US	1838541	26-Mar-03	7043374	
Granted	MFC	U0128-7040	TW	ORD	TW	93108097	25-Mar-04	I241469	
Inactive	MFC	U0128-7040	WO	ORD	PCT	US2004/009144	25-Mar-04		
Granted	MFC	U0128-7040	40	DIV	US	11/051209	04-Feb-05	7272512	18-Sep-07
Published	MFC	U0128-7040	JP	PCT	JP	509282/2006	25-Mar-04		
Abandoned	MFC	U0128-7040	EP	PCT	EP	4758325.7	25-Mar-04		
Abandoned	MFC	U0128-7040	CN	PCT	CN	480014377.7	25-Mar-04		
Abandoned	MFC	U0128-7040	SG	PCT	SG	200506245-0	25-Mar-04		
Inactive	MFC	C2044-7044	EI	DIV	EP	99108929.3	20-Nov-95	940742	10-Apr-02
Abandoned	MFC	C2044-7044	FR	EDV	FR	99108929.3	20-Nov-95	940742	10-Apr-02
Abandoned	MFC	C2044-7044	DE	EDV	DE	99108929.3	20-Nov-95	69526378	10-Apr-02
Abandoned	MFC	C2044-7044	GB	EDV	GB	99108929.3	20-Nov-95	940742	10-Apr-02
Granted	MFC	C2044-7038	JP	ORD	JP	1997-149659	06-Jun-97	4034379	02-Nov-07
Granted	MFC	C2044-7038	19	PRI	US	08/691061	01-Aug-96	5763774	09-Jun-98

State	Product Category	Class	Sub Class	Class	Sub Class	Class	Sub Class	Class	Sub Class	Date
Expired	MFC	C1138-7004	US	PRI	US	07/167572	04-Mar-88	4858643		22-Aug-89
Granted	MFC	C2044-7029	24	CON	US	07/912007	10-Jul-92	5191793		09-Mar-93
Pending	MFC	CINST-7005	19	PRI	United States of America	12/197,888	25-Aug-08			
Expired	MFC	U0128-7029		CON	US	08/758971	02-Dec-96	5730181		24-Mar-98
Abandoned	MFC	C1138-7008	20	CON	US	12/120,975	15-May-08			
Granted	MFC	C1138-7008	19	PRI	US	11/377,911	16-Mar-06	7409871		12-Aug-08
Published	MFC	C1138-7008	TW	ORD	TW	96108901	15-Mar-07			
Abandoned	MFC	C1138-7008	WO	ORD	PCT	US2007/006712	16-Mar-07			
Pending	MFC	C2044-7006	JP	PCT	JP	2001-509947	20-Jun-00			
Granted	MFC	C2044-7006	19	PRI	US	09/350746	09-Jul-99	6575027		10-Jun-03
Abandoned	MFC	C2044-7006	TW	ORD	TW	89113547	07-Jul-00	Ni-131525		28-Aug-01
Granted	MFC	C2044-7006	KR	PCT	KR	2002-7000239	20-Jun-00	10-0684515		13-Feb-07

Abandoned	MFC	MASS FLOW SENSOR INTERFACE CIRCUIT	C2044-7006	EP	PCT	EP	951067.8	20-Jun-00		
Abandoned	MFC	MASS FLOW SENSOR INTERFACE CIRCUIT	C2044-7006	CN	PCT	CN	8011267.3	20-Jun-00		
Abandoned	MFC	MASS FLOW SENSOR INTERFACE CIRCUIT	C2044-7006	SG	PCT	SG	200108047-2	20-Jun-00	85978	30-Jan-04
Expired	MFC	METHOD AND APPARATUS FOR BALANCING RESISTANCE	U0128-7007		PRO	US	60/182306	14-Feb-00		
Granted	MFC	METHOD AND APPARATUS FOR BALANCING RESISTANCE	U0128-7020	TW	ORD	TW	90103216	14-Feb-01	170268	20-May-03
Granted	MFC	METHOD AND APPARATUS FOR BALANCING RESISTANCE	U0128-7020		ORD	US	09/783439	14-Feb-01	6539792	01-Apr-03
Inactive	MFC	METHOD AND APPARATUS FOR BALANCING RESISTANCE	U0128-7020	WO	ORD	PCT	US01/04609	14-Feb-01		
Granted	MFC	METHOD AND APPARATUS FOR BALANCING RESISTANCE	U0128-7020	KR	PCT	KR	2002-7010507	14-Feb-01	10-0808727	22-Feb-08
Pending	MFC	METHOD AND APPARATUS FOR BALANCING RESISTANCE	U0128-7020	JP	PCT	JP	560630/01	14-Feb-01		
Abandoned	MFC	METHOD AND APPARATUS FOR BALANCING RESISTANCE	U0128-7020	EP	PCT	EP	1910613.7	14-Feb-01		
Inactive	MFC	METHOD AND APPARATUS FOR REDUCING HYSTERESIS IN A SOLENOID ACTUATED DEVICE	U0128-7022		PRI	US				

Case Number	Sub Case	Case	Inventor	Sub Class	Case	Case	Case	Case	Case
C2044-7020	19	PRI	US	10/886836	08-Jul-04	7216019	08-May-07		
C2044-7020	TW	ORD	TW	94123276	08-Jul-05				
C2044-7020	WO	ORD	PCT	US2005/024134	07-Jul-05				
C2044-7005	19	PRI	US	09/351111	10-Jul-99	6404612	11-Jun-02		
C2044-7022	0	PRO	US						
U0128-7034		PRO	US	60/397285	19-Jul-02				
U0128-7034	10	ORD	US	10/622080	17-Jul-03	7073392	11-Jul-06		
U0128-7034	42	CON	US	12/233,405	18-Sep-08				

METHOD AND SYSTEM FOR A MASS FLOW CONTROLLER WITH REDUCED PRESSURE SENSITIVITY

METHOD AND SYSTEM FOR A MASS FLOW CONTROLLER WITH REDUCED PRESSURE SENSITIVITY

METHOD AND SYSTEM FOR A MASS FLOW CONTROLLER WITH REDUCED PRESSURE SENSITIVITY

METHOD AND SYSTEM FOR DRIVING A SOLENOID

METHOD FOR COMPENSATING THE TEMPERATURE COEFFICI

METHODS AND APPARATUS FOR PRESSURE COMPENSATION IN A MASS FLOW CONTROLLER

METHODS AND APPARATUS FOR PRESSURE COMPENSATION IN A MASS FLOW CONTROLLER

Methods and Apparatus for Pressure Compensation in a Mass Flow Controller

Granted MFC

Abandoned MFC

Inactive MFC

Granted MFC

Inactive MFC

Expired MFC

Granted MFC

Pending MFC

Patent No.	Title	Applicant	Sub Class	Case Type	Case No.	Priority Date	Pub. No.	Pub. Date
U0128-7034	METHODS AND APPARATUS FOR PRESSURE COMPENSATION IN A MASS FLOW CONTROLLER	MFC	40	DIV	US	11/148053	7273063	08-Jun-05 25-Sep-07
U0128-7034	METHODS AND APPARATUS FOR PRESSURE COMPENSATION IN A MASS FLOW CONTROLLER	MFC	SG	PCT	SG		109196	17-Jul-03 31-Jan-07
U0128-7034	METHODS AND APPARATUS FOR PRESSURE COMPENSATION IN A MASS FLOW CONTROLLER	MFC	CN	PCT	CN	03822352.X		17-Jul-03
U0128-7034	METHODS AND APPARATUS FOR PRESSURE COMPENSATION IN A MASS FLOW CONTROLLER	MFC	G1	DIV	SG	200601750-3		17-Jul-03
U0128-7034	METHODS AND APPARATUS FOR PRESSURE COMPENSATION IN A MASS FLOW CONTROLLER	MFC	EP	PCT	EP	3765703.8		17-Jul-03
U0128-7034	METHODS AND APPARATUS FOR PRESSURE COMPENSATION IN A MASS FLOW CONTROLLER	MFC	WO	ORD	PCT	US2003/022435		17-Jul-03
U0128-7034	METHODS AND APPARATUS FOR PRESSURE COMPENSATION IN A MASS FLOW CONTROLLER	MFC	JP	PCT	JP	523546/2004		17-Jul-03

Status	Priority Date	Case Number	Sub Class	Obs. Type	Country	Application No.	Filing Date	Expiry Date
Abandoned	MFC	U0128-7034	KR	PCT	KR	2005-7000906	17-Jul-03	
Granted	MFC	U0128-7034	41	DIV	US	11/843418	22-Aug-07	14-Oct-08
Granted	MFC	U0128-7034	TW	ORD	TW	92119634	18-Jul-03	01-Nov-04
Inactive	MFC	U0128-7021		PRI	US			
Expired	MFC	U0128-7036		PRO	US	60/406132	27-Aug-02	
Expired	MFC	C1138-7019	0	PRO	US	60/842283	05-Sep-06	
Published	MFC	C1138-7019	10	ORD	US	11/850505	05-Sep-07	
Published	MFC	C1138-7019	TW	ORD	TW	96133001	05-Sep-07	
Published	MFC	C1138-7019	WO	ORD	PCT	US2007/019333	05-Sep-07	
Expired	MFC	U0128-7002		PRO	US	60/143478	12-Jul-99	

Product	Case No.	Applicant	Country	Class	Priority	Pub. Date	Pub. No.	Pub. Date	Pub. No.
Inactive	MFC	U0128-7016	50	REX	US				
		PRESSURE INSENSITIVE GAS CONTROL SYSTEM							
Granted	MFC	U0128-7016	TW	ORD	TW	89113822	12-Jul-00	130212	08-Aug-01
		PRESSURE INSENSITIVE GAS CONTROL SYSTEM							
Granted	MFC	U0128-7016	JP	PCT	JP	509951/01	12-Jul-00	3615517	12-Nov-04
		PRESSURE INSENSITIVE GAS CONTROL SYSTEM							
Abandoned	MFC	U0128-7016	EP	PCT	EP	945351.5	12-Jul-00		
		PRESSURE INSENSITIVE GAS CONTROL SYSTEM							
Granted	MFC	U0128-7016		ORD	US	09/616819	12-Jul-00	6425281	30-Jul-02
		PRESSURE INSENSITIVE GAS CONTROL SYSTEM							
Inactive	MFC	U0128-7016	WO	ORD	PCT	US00/19028	12-Jul-00		
		PRESSURE INSENSITIVE GAS CONTROL SYSTEM							
Abandoned	MFC	U0128-7033		CON	US	10/187411	01-Jul-02		
		PRESSURE INSENSITIVE GAS CONTROL SYSTEM							
Published	MFC	C2044-7016	IC	DIV	CN	2.0081000135e+011	23-May-03		
		SLOTTED FLOW RESTRICTOR FOR A MASS FLOW METER (as amended by the ISA in the ISR dated 9-16-03)							
Abandoned	MFC	C2044-7016	CN	PCT	CN	ZL03814867.6	23-May-03		
		SLOTTED FLOW RESTRICTOR FOR A MASS FLOW METER (as amended by the ISA in the ISR dated 9-16-03)							
Pending	MFC	C2044-7016	JP	PCT	JP	2004-507769	23-May-03		
		SLOTTED FLOW RESTRICTOR FOR A MASS FLOW METER (as amended by the ISA in the ISR dated 9-16-03)							
Abandoned	MFC	C2044-7016	TW	ORD	TW	92114020	23-May-03	1280354	01-May-07
		SLOTTED FLOW RESTRICTOR FOR A MASS FLOW METER (as amended by the ISA in the ISR dated 9-16-03)							

State	Patent Class	Case Number	Sub Class	Country	Pub No	Pub Date	Pub Date		
Granted	MFC	C2044-7016	US	PCT	US	10/515328	23-May-03	7124647	24-Oct-06
Expired	MFC	U0128-7017	US	PRO	US	60/285801	24-Apr-01		
Granted	MFC	U0128-7030	40	DIV	US	11/092144	29-Mar-05	7114511	03-Oct-06
Abandoned	MFC	U0128-7030	CN	PCT	CN	2810540	24-Apr-02		
Abandoned	MFC	U0128-7030	EP	PCT	EP	2764338.6	24-Apr-02		
Pending	MFC	U0128-7030	JP	PCT	JP	2002-584094	24-Apr-02		
Granted	MFC	U0128-7030	21	CON	US	11/749386	16-May-07	7380564	03-Jun-08
Granted	MFC	U0128-7030	20	CON	US	11/091824	28-Mar-05	7231931	19-Jun-07
Granted	MFC	U0128-7030		ORD	US		24-Apr-02	6962164	08-Nov-05
Granted	MFC	U0128-7030	TW	ORD	TW	91108305	23-Apr-02	181838	12-Nov-03
Inactive	MFC	U0128-7030	WO	ORD	PCT	US02/13010	24-Apr-02		
Abandoned	MFC	U0128-7030	KR	PCT	KR	2003-7014001	24-Apr-02		

Patent No.	App. No.	Pub. No.	Pub. Date	App. No.	Pub. No.	Pub. Date	App. No.	Pub. No.	Pub. Date
Inactive	MFC	U0128-7060	E1	DIV	EP	4002135.4	24-Apr-02	1457856	23-Nov-05
Granted	MFC	U0128-7060	DE	EDV	DE	4002135.4	24-Apr-02	60207609.9	23-Nov-05
Granted	MFC	U0128-7060	IE	EDV	IE	4002135.4	24-Apr-02	1457856	23-Nov-05
Granted	MFC	U0128-7060	NL	EDV	NL	4002135.4	24-Apr-02	1457856	23-Nov-05
Abandoned	MFC	C2044-7004	SG	PCT	SG	200108045-6	21-Jun-00	85977	27-Feb-04
Granted	MFC	C2044-7004	19	PRI	US	09/351098	10-Jul-99	6445980	03-Sep-02
Abandoned	MFC	C2044-7004	TW	ORD	TW	89113538	10-Jul-00	NI-156972	27-Sep-02
Abandoned	MFC	C2044-7004	NL	EPP	NL	955906.3	21-Jun-00	1196833	27-Aug-03
Granted	MFC	C2044-7004	KR	PCT	KR	2002-7000370	21-Jun-00	10-0621830	13-Sep-06

Patent Class.	Sub Class.	App. No.	Pub. No.	Pub. Date	Pub. Date	Pub. Date				
Abandoned	MFC	SYSTEM AND METHOD FOR A VARIABLE GAIN PROPORTIONAL-INTEGRAL (PI) CONTROLLER	C2044-7004	IT	EPP	IT	955906.3	21-Jun-00	1196833	27-Aug-03
Abandoned	MFC	SYSTEM AND METHOD FOR A VARIABLE GAIN PROPORTIONAL-INTEGRAL (PI) CONTROLLER	C2044-7004	DE	EPP	DE	955906.3	21-Jun-00	60004855.1	27-Aug-03
Abandoned	MFC	SYSTEM AND METHOD FOR A VARIABLE GAIN PROPORTIONAL-INTEGRAL (PI) CONTROLLER	C2044-7004	FR	EPP	FR	955906.3	21-Jun-00	1196833	27-Aug-03
Inactive	MFC	SYSTEM AND METHOD FOR A VARIABLE GAIN PROPORTIONAL-INTEGRAL (PI) CONTROLLER	C2044-7004	EP	PCT	EP	955906.3	21-Jun-00	1196833	27-Aug-03
Abandoned	MFC	SYSTEM AND METHOD FOR A VARIABLE GAIN PROPORTIONAL-INTEGRAL (PI) CONTROLLER	C2044-7004	CN	PCT	CN	810175.2	21-Jun-00	810175.2	04-Jan-06
Abandoned	MFC	SYSTEM AND METHOD FOR A VARIABLE GAIN PROPORTIONAL-INTEGRAL (PI) CONTROLLER	C2044-7004	GB	EPP	GB	955906.3	21-Jun-00	1196833	27-Aug-03
Pending	MFC	SYSTEM AND METHOD FOR FILTERING OUTPUT IN MASS FLOW CONTROLLERS AND MASS FLOW METERS	C2044-7010	JP	PCT	JP	2001-510061	21-Jun-00		
Abandoned	MFC	SYSTEM AND METHOD FOR FILTERING OUTPUT IN MASS FLOW CONTROLLERS AND MASS FLOW METERS	C2044-7010	10	ORD	US	50679	26-Apr-02	6865520	08-Mar-05

System	Product	Case Number	Applicant	Country	Pub. No.	Pub. Date	Pub. No.	Pub. Date
Granted	MFC	C2044-7010	20	CON	US	2723524	26-Aug-04	7113895
Granted	MFC	C2044-7015	CN	PCT	CN	3814900.1	23-May-03	ZL03814900.1
Granted	MFC	C2044-7015	20	CON	US	11/129166	13-May-05	7363182
Granted	MFC	C2044-7015	10	ORD	US	10/444249	23-May-03	7243035
Abandoned	MFC	C2044-7015	TW	ORD	TW	92113996	23-May-03	I274143
Pending	MFC	C2044-7015	KR	PCT	KR	2004-7019027	23-May-03	
Abandoned	MFC	C2044-7015	EP	PCT	EP	3734166.6	23-May-03	
Pending	MFC	C2044-7015	JP	PCT	JP	2004-507802	23-May-03	
Abandoned	MFC	C2044-7015	SG	PCT	SG	200406847-4	23-May-03	108077

Patent No.	Pub. No.	Pub. Date	App. No.	App. Date	Pub. No.	Pub. Date	App. No.	App. Date	Pub. No.	Pub. Date	App. No.	App. Date
Granted	MFC	C2044-7008	KR	PCT	KR	2002-7000306	2002-7000306	20-Jun-00	10-0620282	29-Aug-06		
Granted	MFC	C2044-7008	19	PRJ	US	09/350747	09/350747	09-Jul-99	6449571	10-Sep-02		
Abandoned	MFC	C2044-7008	SG	PCT	SG	200108042-3	200108042-3	20-Jun-00	85974	30-Jan-04		
Pending	MFC	C2044-7008	JP	PCT	JP	2001-509948	2001-509948	20-Jun-00				
Abandoned	MFC	C2044-7008	EP	PCT	EP	951068.6	951068.6	20-Jun-00				
Abandoned	MFC	C2044-7008	CN	PCT	CN	810113.2	810113.2	20-Jun-00	810113.2	15-Jun-05		
Abandoned	MFC	C2044-7008	TW	ORD	TW	89113537	89113537	07-Jul-00	NI-133298	26-Sep-01		
Abandoned	MFC	C2044-7003	ID	EDV	DE	3016602.9	3016602.9	21-Jun-00	60036649.9	03-Oct-07		
Abandoned	MFC	C2044-7003	40	DIV	US	09/755994	09/755994	05-Jan-01				
Granted	MFC	C2044-7003	20	CON	US	1780467	1780467	06-Dec-01	6681787	27-Jan-04		
Granted	MFC	C2044-7003	19	PRJ	US	09/350744	09/350744	09-Jul-99	6343617	05-Feb-02		

Patent Status	Case Title	Case Number	Sub Class	Priority	Publication No.	Priority Date	Pub Date	Pub No.	Pub No.
Abandoned	SYSTEM AND METHOD OF OPERATION OF A DIGITAL MASS FLOW CONTROLLER	C2044-7003	SG	PCT	200108048-0	21-Jun-00	85979	85979	31-Mar-04
Abandoned	SYSTEM AND METHOD OF OPERATION OF A DIGITAL MASS FLOW CONTROLLER	C2044-7003	IG	EDV	3016602.9	21-Jun-00	1359487	1359487	03-Oct-07
Granted	SYSTEM AND METHOD OF OPERATION OF A DIGITAL MASS FLOW CONTROLLER	C2044-7003	41	DIV	225265	05-Feb-02	6640822	6640822	04-Nov-03
Abandoned	SYSTEM AND METHOD OF OPERATION OF A DIGITAL MASS FLOW CONTROLLER	C2044-7003	TW	ORD	89113546	07-Jul-00	NI-154643	NI-154643	01-May-02
Granted	SYSTEM AND METHOD OF OPERATION OF A DIGITAL MASS FLOW CONTROLLER	C2044-7003	KR	PCT	2002-7000296	21-Jun-00	10-0718209	10-0718209	15-May-07
Pending	SYSTEM AND METHOD OF OPERATION OF A DIGITAL MASS FLOW CONTROLLER	C2044-7003	JP	PCT	2001-510059	21-Jun-00			
Abandoned	SYSTEM AND METHOD OF OPERATION OF A DIGITAL MASS FLOW CONTROLLER	C2044-7003	II	EDV	3016602.9	21-Jun-00	1359487	1359487	03-Oct-07
Abandoned	SYSTEM AND METHOD OF OPERATION OF A DIGITAL MASS FLOW CONTROLLER	C2044-7003	F1	EDV	3016602.9	21-Jun-00	1359487	1359487	03-Oct-07
Abandoned	SYSTEM AND METHOD OF OPERATION OF A DIGITAL MASS FLOW CONTROLLER	C2044-7003	E1	DIV	3016602.9	21-Jun-00	1359487	1359487	03-Oct-07
Abandoned	SYSTEM AND METHOD OF OPERATION OF A DIGITAL MASS FLOW CONTROLLER	C2044-7003	CN	PCT	811323.8	21-Jun-00	811323.8	811323.8	05-Apr-06

Serial	Title	IPC Class.	Pub. No.	Pub. Date	Int. Class.	Pub. No.	Pub. Date	Pub. No.	Pub. Date	
Abandoned	SYSTEM AND METHOD OF OPERATION OF A DIGITAL MASS FLOW CONTROLLER	MFC	C2044-7003	II	EDV	IT	3016602.9	21-Jun-00	1359487	03-Oct-07
Abandoned	SYSTEM AND METHOD OF OPERATION OF A DIGITAL MASS FLOW CONTROLLER	MFC	C2044-7003	N1	EDV	NL	3016602.9	21-Jun-00	1359487	03-Oct-07
Inactive	SYSTEM AND METHOD OF OPERATION OF A DIGITAL MASS FLOW CONTROLLER	MFC	C2044-7028	EP	PCT	EP	939986.6	21-Jun-00	1212665	08-Oct-03
Abandoned	SYSTEM AND METHOD OF OPERATION OF A DIGITAL MASS FLOW CONTROLLER	MFC	C2044-7028	FR	EPP	FR	939986.6	21-Jun-00	1212665	08-Oct-03
Abandoned	SYSTEM AND METHOD OF OPERATION OF A DIGITAL MASS FLOW CONTROLLER	MFC	C2044-7028	DE	EPP	DE	939986.6	21-Jun-00	60005849.2	08-Oct-03
Abandoned	SYSTEM AND METHOD OF OPERATION OF A DIGITAL MASS FLOW CONTROLLER	MFC	C2044-7028	IE	EPP	IE	939986.6	21-Jun-00	1212665	08-Oct-03
Abandoned	SYSTEM AND METHOD OF OPERATION OF A DIGITAL MASS FLOW CONTROLLER	MFC	C2044-7028	IT	EPP	IT	939986.6	21-Jun-00	1212665	08-Oct-03
Abandoned	SYSTEM AND METHOD OF OPERATION OF A DIGITAL MASS FLOW CONTROLLER	MFC	C2044-7028	NL	EPP	NL	939986.6	21-Jun-00	1212665	08-Oct-03
Abandoned	SYSTEM AND METHOD OF OPERATION OF A DIGITAL MASS FLOW CONTROLLER	MFC	C2044-7028	GB	EPP	GB	939986.6	21-Jun-00	1212665	08-Oct-03
Pending	System for and Method of Providing a Wide-Range Flow Controller	MFC	C1138-7020	10	ORD	US	12/249,821	10-Oct-08		

Patent Class	Patent No.	Sub Class	Applicant No.	Country	Order Type	Order No.	Issue Date	Priority Date
Expired	MFC	0	C1138-7020	US	PRO	60/978956	10-Oct-07	
Pending	MFC	10	CINST-7001	United States of America	ORD	12/193,584	18-Aug-08	
Pending	MFC	0	CINST-7001	United States of America	PRO	61/080,270	13-Jul-08	
Abandoned	MFC	DE	U0128-7013	DE	EPC	93924335.8	15-Oct-93	05-Jan-00
Abandoned	MFC	GB	U0128-7013	GB	EPC	93924335.8	15-Oct-93	05-Jan-00
Granted	MFC	KR	U0128-7013	KR	PCT	701451/1995	15-Oct-93	28-Jan-02
Abandoned	MFC	IT	U0128-7013	IT	EPC	93924335.8	15-Oct-93	05-Jan-00

SYSTEM FOR AND METHODS OF PROVIDING A WIDE-RANGE FLOW CONTROLLER

Thermal Flow Meter

Thermal Mass Flow Controller
THERMAL MASS FLOW CONTROLLER HAVING ORTHOGONAL THERMAL MASS FLOW SENSOR

THERMAL MASS FLOW CONTROLLER HAVING ORTHOGONAL THERMAL MASS FLOW SENSOR
THERMAL MASS FLOW CONTROLLER HAVING ORTHOGONAL THERMAL MASS FLOW SENSOR
THERMAL MASS FLOW CONTROLLER HAVING ORTHOGONAL THERMAL MASS FLOW SENSOR

Patent Status	Title	Class Number	Country	Applicant	Priority Date	Pub. No.	Pub. Date
Abandoned	THERMAL MASS FLOW CONTROLLER HAVING ORTHOGONAL THERMAL MASS FLOW SENSOR	U0128- 7013	FR	93924335.8	15-Oct-93	664879	05-Jan-00
Inactive	THERMAL MASS FLOW CONTROLLER HAVING ORTHOGONAL THERMAL MASS FLOW SENSOR	U0128- 7013	EP	93924335.8	15-Oct-93	664879	05-Jan-00
Granted	THERMAL MASS FLOW CONTROLLER HAVING ORTHOGONAL THERMAL MASS FLOW SENSOR	U0128- 7013	JP	510311/94	15-Oct-93	3279567	22-Feb-02
Granted	THERMAL MASS FLOW CONTROLLER HAVING ORTHOGONAL THERMAL MASS FLOW SENSOR	U0128- 7014	US	08/815323	10-Mar-97	6044701	04-Apr-00
Abandoned	THERMAL MASS FLOW CONTROLLER HAVING ORTHOGONAL THERMAL MASS FLOW SENSOR	U0128- 7015	US	09/499762	08-Feb-00		
Granted	VALVE CONTROL SYSTEM AND METHOD	C2044- 7019	US	10/887040	08-Jul-04	7133785	07-Nov-06
Abandoned	VALVE CONTROL SYSTEM AND METHOD	C2044- 7019	CN	2.0058002996e+011	07-Jul-05		
Abandoned	VALVE CONTROL SYSTEM AND METHOD	C2044- 7019	EP	5769581.9	07-Jul-05		
Abandoned	VALVE CONTROL SYSTEM AND METHOD	C2044- 7019	JP	520482/2007	07-Jul-05		
Pending	VALVE CONTROL SYSTEM AND METHOD	C2044- 7019	KR	2007-7002967	07-Jul-05		
Inactive	VALVE CONTROL SYSTEM AND METHOD	C2044- 7019	WO	US2005/024033	07-Jul-05		

State	Patent Title	Case Number	Case Title	Case Type	Applicant	Date	Case No.	Case Title	Date	Case No.	Case Title	Date
Abandoned	MFC	C2044-7019	VALVE CONTROL SYSTEM AND METHOD	SG PCT	200700115-9	07-Jul-05	SG	PCT				
Abandoned	MFC	C2044-7019	VALVE CONTROL SYSTEM AND METHOD	TW ORD	94123259	08-Jul-05	TW	ORD				
Expired	MFC	U0128-7025	VARIABLE RESISTANCE SENSOR WITH COMMON REFERENCE LEG	PRO	60/397139	19-Jul-02		PRO	US			
Expired	MFC	U0128-7039	VARIABLE RESISTANCE SENSOR WITH COMMON REFERENCE LEG	PRO	60/436207	23-Dec-02		PRO	US			
Granted	MFC	U0128-7039	VARIABLE RESISTANCE SENSOR WITH COMMON REFERENCE LEG	CON	10/978156	29-Oct-04	20	CON	US	7082824		01-Aug-06
Granted	MFC	U0128-7039	VARIABLE RESISTANCE SENSOR WITH COMMON REFERENCE LEG	ORD	10/622004	16-Jul-03	10	ORD	US	6845659		25-Jan-05
Abandoned	MFC	U0128-7039	VARIABLE RESISTANCE SENSOR WITH COMMON REFERENCE LEG	SG PCT		16-Jul-03	SG	PCT		109197		31-Aug-07
Inactive	MFC	U0128-7039	VARIABLE RESISTANCE SENSOR WITH COMMON REFERENCE LEG	WO ORD	US2003/022337	16-Jul-03		ORD	PCT			
Abandoned	MFC	U0128-7039	VARIABLE RESISTANCE SENSOR WITH COMMON REFERENCE LEG	KR PCT	2005-7001009	16-Jul-03	KR	PCT	KR			
Abandoned	MFC	U0128-7039	VARIABLE RESISTANCE SENSOR WITH COMMON REFERENCE LEG	EP PCT	3765648.5	16-Jul-03	EP	PCT	EP			
Abandoned	MFC	U0128-7039	VARIABLE RESISTANCE SENSOR WITH COMMON REFERENCE LEG	CN PCT	03819614.X	16-Jul-03	CN	PCT	CN	03819614.X		24-Oct-07
Granted	MFC	U0128-7039	VARIABLE RESISTANCE SENSOR WITH COMMON REFERENCE LEG	TW ORD	92119635	18-Jul-03	TW	ORD	TW	I222514		21-Oct-04
Pending	MFC	U0128-7039	VARIABLE RESISTANCE SENSOR WITH COMMON REFERENCE LEG	JP PCT	523492/2004	16-Jul-03	JP	PCT	JP			
Abandoned	Other	C1138-7003	GAS FLOW CONTROL APPARATUS	US PRI	1092990	03-Apr-89	US	PRI	US	4913192		03-Apr-90

Patent Status	Product Class	Inventor	Sub Class	Country	App. No.	Date	Pub. No.	Pub. Date
Granted	Other	C2044-7043	70	US	29/057079	16-Jul-96	D390138	03-Feb-98
Expired	Pressure	C2044-7041	19	US	1435586	21-Jan-87	4898036	06-Feb-90
Granted	Pressure	C2044-7033	19	US	09/291468	14-Apr-99	6319743	20-Nov-01
Abandoned	Pressure	C2044-7033	EP	EP	925951.6	13-Apr-00		
Abandoned	Pressure	C2044-7033	JP	JP	2000-611045	13-Apr-00	3730868	14-Oct-05
Abandoned	Pressure	C2044-7033	KR	KR	2001-7013160	13-Apr-00	432465	11-May-04
Abandoned	Pressure	C2044-7033	TW	TW	89106988	28-Apr-00	NI-145002	01-Aug-01
Abandoned	Pressure	C2044-7033	SG	SG	200106292-6	13-Apr-00	84198	31-May-04
Expired	Pressure	C2044-7040	19	US	1394649	28-Oct-85	4745811	24-May-88
Pending	Pressure	C2044-7018	SG	SG		11-Apr-05		
Abandoned	Pressure	C2044-7018	CN	CN	580011775.8	11-Apr-05		
Pending	Pressure	C2044-7018	TW	TW	94112264	18-Apr-05		

Patent Status	Priority Country	Class Number	Sub Class	Pub No.	Pub Date	Pub Date	Pub Date
Inactive	RFS	U0128-7031	WO	ORD	PCT	US02/16289	23-May-02
Abandoned	RFS	U0128-7031	KR	PCT	KR	2003-7014994	23-May-02
Granted	RFS	U0128-7031	JP	PCT	JP	2002-591927	23-May-02
Granted	RFS	U0128-7031	JP	ORD	US	10/154433	23-May-02
Abandoned	RFS	U0128-7031	EP	PCT	EP	279349.5	23-May-02
Published	RFS	U0128-7031	J1	DIV	JP	2008-027621	23-May-02
Abandoned	ROR	U0128-7041		CON	US	689062	03-Feb-97
Expired	Vacuum	C2044-7037	19	PRI	US	06/736224	20-May-85
Published	Vacuum	C2044-7013	CN	PCT	CN	ZL03817033.7	11-Jun-03

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Pending	Vacuum	AN IMPROVED TEMPERATURE REGULATOR FOR USE WITH A PRESSURE SENSING DEVICE	C2044-7012	JP	PCT	JP	2004-513064	12-Jun-03		
Abandoned	Vacuum	AN IMPROVED TEMPERATURE REGULATOR FOR USE WITH A PRESSURE SENSING DEVICE	C2044-7012	TW	ORD	TW	92115978	12-Jun-03		
Abandoned	Vacuum	AN IMPROVED TEMPERATURE REGULATOR FOR USE WITH A PRESSURE SENSING DEVICE	C2044-7012	CN	PCT	CN	3816966.5	12-Jun-03	3816966.5	25-Apr-08
Granted	Vacuum	AN IMPROVED TEMPERATURE REGULATOR FOR USE WITH A PRESSURE SENSING DEVICE	C2044-7012	19	PRI	US		13-Jun-02	6701790	09-Mar-04
Granted	Vacuum	MANOMETER HAVING STRESS RELIEVE FOR FIXED ELECTRODE CAPACITANCE	C2044-7047	FR	ORD	FR	8809402	11-Jul-88	8809402	03-Sep-93
Granted	Vacuum	MANOMETER HAVING STRESS RELIEVE FOR FIXED ELECTRODE CAPACITANCE	C2044-7047	DE	ORD	DE	P3838333-0	11-Nov-88	3838333	10-Dec-90
Granted	Vacuum	MANOMETER HAVING STRESS RELIEVE FOR FIXED ELECTRODE CAPACITANCE	C2044-7047	JP	ORD	JP	63-280250	04-Nov-88	1701368	14-Oct-92
Abandoned	Vacuum	MANOMETER HAVING STRESS RELIEVE FOR FIXED ELECTRODE CAPACITANCE	C2044-7047	KR	ORD	KR	16383/88	09-Dec-88	66935	26-Oct-93
Expired	Vacuum	MANOMETER HAVING STRESS RELIEVE FOR FIXED ELECTRODE CAPACITANCE	C2044-7047	19	PRI	US	07/189780	03-May-88	4823603	25-Apr-89

Abandoned	Vacuum	DEVICE AND SYSTEM FOR PRESSURE SENSING AND CONTROL	C2044-7011	19	PRI	US	10/805742	22-Mar-04	
Granted	Vacuum	DUAL BALANCED CAPACITANCE MANOMETERS FOR SUPPRESSING VIBRATION EFFECTS ELECTRONIC	C2044-7035	19	PRI	US	08/088317	07-Jul-93	5396803 14-Mar-95
Pending	Vacuum	INTERFACE FOR USE WITH DUAL ELECTRODE CAPACITANCE DIAPHRAGM GAUGES ELECTRONIC	C2044-7013	JP	PCT	JP	2004-513790	11-Jun-03	
Abandoned	Vacuum	INTERFACE FOR USE WITH DUAL ELECTRODE CAPACITANCE DIAPHRAGM GAUGES ELECTRONIC	C2044-7013	TW	ORD	TW	92115982	12-Jun-03	
Granted	Vacuum	INTERFACE FOR USE WITH DUAL ELECTRODE CAPACITANCE DIAPHRAGM GAUGES SYSTEM AND METHOD OF OPERATION OF AN EMBEDDED SYSTEM FOR A DIGITAL CAPACITANCE DIAPHRAGM GAUGE	C2044-7013	19	PRI	US	474540	13-Jun-02	6734659 11-May-04
Pending	Vacuum	SYSTEM AND METHOD OF OPERATION OF AN EMBEDDED SYSTEM FOR A DIGITAL CAPACITANCE DIAPHRAGM GAUGE SYSTEM AND METHOD OF OPERATION OF AN EMBEDDED SYSTEM FOR A DIGITAL CAPACITANCE DIAPHRAGM GAUGE	C2044-7014	KR	PCT	KR	2004-7019462	29-May-03	
Granted	Vacuum	SYSTEM AND METHOD OF OPERATION OF AN EMBEDDED SYSTEM FOR A DIGITAL CAPACITANCE DIAPHRAGM GAUGE	C2044-7014	40	DIV	US	10/848739	19-May-04	7010983 14-Mar-06

Class	Pub. No.	Pub. Date	App. No.	App. Date	Pub. No.	Pub. Date	App. No.	App. Date	Pub. No.	Pub. Date	App. No.	App. Date
Granted	Vacuum	C2044-7014	21	CON	US	11/369,885	07-Mar-06	7490518				17-Feb-09
Published	Vacuum	C2044-7014	20	CON	US	11/321,238	29-Dec-05					
Granted	Vacuum	C2044-7014	19	PRI	US	-527500	31-May-02	6910381				28-Jun-05
Abandoned	Vacuum	C2044-7014	SG	PCT	SG	200406848-2	29-May-03	108078				31-Jan-08
Pending	Vacuum	C2044-7014	JP	PCT	JP	2004-509366	29-May-03					
Abandoned	Vacuum	C2044-7014	EP	PCT	EP	3731440.8	29-May-03					

Patent Class.	Patent Title	Case Number	Sub Class	Priority	Country	Applicant No.	Issue Date	Grant Date
Abandoned	Vacuum	C2044-7014	CN	PCT	CN	03815563.X	29-May-03	
Abandoned	Vacuum	C2044-7014	TW	ORD	TW	92114786	30-May-03	
Granted	Valve	C2044-7036	19	PRI	US	07701200	16-May-91	02-Jun-92
Abandoned	Valve	10294-7003		PRI	US	08/404485	17-Mar-95	25-Feb-97
Inactive	Valve	10294-7003	WO	ORD	PCT	US96/01945	13-Feb-96	
Abandoned	Valve	C2044-7009	TW	ORD	TW	91108434	24-Apr-02	09-Sep-03
Granted	Valve	C2044-7009	10	ORD	US	09/952083	12-Sep-01	28-Feb-06
Granted	Valve	C2044-7042	19	PRI	US	07/872350	23-Apr-92	15-Jun-93
Abandoned	Valve	C2044-7034	JP	ORD	JP	1992-350321	01-Dec-92	01-Feb-02
Granted	Valve	C2044-7034	19	PRI	US	08/078365	16-Jun-93	09-May-95
Granted	Valve	C2044-7039	19	PRI	US	08/682170	16-Jul-96	28-Jul-98
Published	WVDM	C2044-7030	19	PRI	US	11/349,068	07-Feb-06	

System	Trade Name	Title	Case Number	Sub Class	IPC Class	Publication No.	Pub Date
Abandoned	WVDM	VAPOR DELIVERY SYSTEM AND METHOD	C2044-7030	WO	ORD	US2007/003143	07-Feb-07
Pending	WVDM	VAPOR DELIVERY SYSTEM AND METHOD	C2044-7030	TW	ORD	96104382	07-Feb-07